

PREFACE

The papers in this volume constitute the Proceedings of the 14th International Conference on Defects-Recognition, Imaging and Physics in Semiconductors (DRIP-XIV). The conference was held at Miyazaki City on September 25-29, chaired by Prof. Michio Tajima.

The volume comprises the original papers critically reviewed by the experts in the field. Every paper was subjected to and passed through the peer review by at least two referees. A thousand of emails were sent between the authors, reviewers and the editors to accomplish the peer review of the papers. Finally the editors have decided to include 66 papers as the contributions to this volume. It documents fresh understanding of the many topics of current interests in science and technology of defects in semiconductors. The investigation of the defects in semiconductors appears to be a little different from other field of materials science: In order to observe the defects in semiconductors and to disclose their physical reality, a very wide variety of tools and techniques are introduced or created based on the flexible ideas of the researchers. The editors believe that this volume clearly demonstrates such the animated investigation of the defects in semiconductors. The editors are very happy to participate in editing this volume of the excellent papers. They are also grateful to the contributors and the reviewers of the papers.

It should be noted finally that the issue of this volume of the proceedings, as well as the conference itself, owes very much the organizing committees and the attendees of the conference who proactively came together to Japan which was just in the confusion by the terrible accident of the nuclear power plant in Fukushima.

Hiroshi Yamada-Kaneta

Akira Sakai,

Message from New General Chair

(Reproduced from the DRIP web page)

Subject: DRIP-XIV Restart

Date: March 31, 2011

Dear Colleagues,

I am writing to inform you that we have decided to continue our planning for DRIP-XIV. The conference will be held at the originally scheduled time and venue: September 25-29, 2011 in Miyazaki. Because of the earthquake tragedy and nuclear power plant accident, please understand that we may have to reduce the size of the conference and have moved the site from the Phoenix Seagaia Resort. However, all the new members of the Organizing Committee have a very strong will to continue organizing DRIP-XIV successfully as originally scheduled.

The general chair, Professor Takashi Sekiguchi, has expressed his desire to step down because of serious damage to his office as well as the residences of relatives. I have thus taken his responsibilities, and he has also stepped aside as a member of the advisory board. I hope that members of the International Steering Committee are willing to accept this change. New members of the Organizing Committee are Professors Koichi Kakimoto and Hiroshi Yamada-Kaneta, and we will also have strong support from the members of the JSPS 145th Committee, the sponsor of DRIP-XIV.

Although the aftermath is at this time really terrible, we consider it our duty as scientists to promote our research activity as part of the full recovery of Japan. The organization of international conferences like DRIP is very helpful in encouraging young researchers, which is perhaps particularly important at this time in history. I do hope all of you will be able to attend DRIP-XIV to encourage them. I believe that the Government will continue to control the nuclear-plant issues so that they will be calmed down and safe by September. Let me remind you that Miyazaki is more than 1,000 km away from the Fukushima plant.

Details will be uploaded onto the new website: <http://fukuoka.riam.kyushu-u.ac.jp/drip14/>.

It would be a great help if we were able to estimate, at least approximately, the number of those who would plan to participate, especially from foreign countries. Please let me know the possibility of your attendance at the present stage. An approximate number of participants from your country would also be quite helpful. Again, I would greatly appreciate your participation.

Finally, we would like to express our sincere gratitude for your sympathy and condolences.

I would appreciate your kind reply at your earliest convenience.

Sincerely yours,

Michio Tajima

General Chair of DRIP-XIV

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